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L Number	Hits	Search Text	DB	Time stamp
1	8842	yield$1 same threshold	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 19:50
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3	0	hamalainen.in. and henriksson.in. and (yield$1 same threshold)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 19:56
4	6	(artificial adj neural adj network) and (pattern$1 same recogni$4 same classif$7) and (expert$1 adj system$1) and (knowledge adj base$1) and (yield$1 same threshold)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 19:57
5	6	((expert$1 adj system$1) same (knowledge adj base$1)) and ((artificial adj neural adj network) same (pattern$1 same recogni$4 same classif$7)) and (yield$1 same threshold)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 19:57
6	15	706/20.ccls. and (yield$1 same threshold)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 19:58
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-	2	ARATHORN-David-W.in.	USPAT; US-PGPUB	2004/05/10 12:33

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-	443	henriksson.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 12:45
-	6	hamalainen.in. and henriksson.in.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 19:56
-	2540	artificial adj neural adj network	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:28
-	3756	pattern$1 same recogni$4 same classif$7	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:30
-	14510	production adj yield	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:30
-	39416	produc$4 adj yield$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:31
-	8175	expert$1 adj system$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:37
-	9765	knowledge adj base$1	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:38

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-	27	US-5237508-$.DID. US-4958292-$.DID. US-4802094-$.DID. US-6269354-$.DID. US-6266668-$.DID. US-6262678-$.DID. US-6249755-$.DID. US-6216119-$.DID. US-5892808-$.DID. US-5835902-$.DID. US-5761383-$.DID. US-5748847-$.DID. US-5586033-$.DID. US-5528516-$.DID. US-5467428-$.DID. US-5448684-$.DID. US-5390261-$.DID. US-5376963-$.DID. US-5355435-$.DID. US-5253329-$.DID. US-5251268-$.DID. US-5214745-$.DID. US-4876731-$.DID. WO-0072449$.did. WO-9854653$.did. WO-9843159$.did. US-4874963-$.DID. US-4642782-$.DID. US-4660166-$.DID. and (pattern$1 same recogni$4 same classif$7)	USPAT; US-PGPUB; EPO	2004/05/10 13:39
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-	33	(artificial adj neural adj network) and (pattern$1 same recogni$4 same classif$7) and (expert$1 adj system$1) and (knowledge adj base$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 19:57
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-	0	hamalainen.in. and henriksson.in. and ((artificial adj neural adj network) and (pattern$1 same recogni$4 same classif$7) and (expert$1 adj system$1) and (knowledge adj base$1))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:52
-	1472	(expert$1 adj system$1) same (knowledge adj base$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:56

-	156	(artificial adj neural adj network) same (pattern$1 same recogni$4 same classif$7)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:56
-	94	(artificial adj neural adj network) same (expert$1 adj system$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:56
-	67	(pattern$1 same recogni$4 same classif$7) same (expert$1 adj system$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 13:56
-	12	((expert$1 adj system$1) same (knowledge adj base$1)) and ((artificial adj neural adj network) same (pattern$1 same recogni$4 same classif$7))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 19:57
-	2	(((expert$1 adj system$1) same (knowledge adj base$1)) and ((artificial adj neural adj network) same (pattern$1 same recogni$4 same classif$7))) and (produc$4 adj yield$1)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 14:00
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-	0	364/*.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:06

-	0	364/$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:08
-	492	706/20.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 19:58
-	5	(US-5237508-$.DID. US-4958292-$.DID. US-4802094-$.DID. US-6269354-$.DID. US-6266668-$.DID. US-6262678-$.DID. US-6249755-$.DID. US-6216119-$.DID. US-5892808-$.DID. US-5835902-$.DID. US-5761383-$.DID. US-5748847-$.DID. US-5586033-$.DID. US-5528516-$.DID. US-5467428-$.DID. US-5448684-$.DID. US-5390261-$.DID. US-5376963-$.DID. US-5355435-$.DID. US-5253329-$.DID. US-5251268-$.DID. US-5214745-$.DID. US-4876731-$.DID. WO-0072449$.did. WO-9854653$.did. WO-9843159$.did. US-4874963-$.DID. US-4642782-$.DID. US-4660166-$.DID.) and 706/20.ccls.	USPAT; US-PGPUB; EPO	2004/05/10 15:14
-	0	hamalainen.in. and henriksson.in. and 706/20.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:14
-	2	(artificial adj neural adj network) and (pattern$1 same recogni$4 same classif$7) and (expert$1 adj system$1) and (knowledge adj base$1) and 706/20.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:14
-	1	((expert$1 adj system$1) same (knowledge adj base$1)) and ((artificial adj neural adj network) same (pattern$1 same recogni$4 same classif$7)) and 706/20.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:14
-	28292	702/$.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:13
-	557	702/183.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:13
-	1	(US-5237508-$.DID. US-4958292-$.DID. US-4802094-$.DID. US-6269354-$.DID. US-6266668-$.DID. US-6262678-$.DID. US-6249755-$.DID. US-6216119-$.DID. US-5892808-$.DID. US-5835902-$.DID. US-5761383-$.DID. US-5748847-$.DID. US-5586033-$.DID. US-5528516-$.DID. US-5467428-$.DID. US-5448684-$.DID. US-5390261-$.DID. US-5376963-$.DID. US-5355435-$.DID. US-5253329-$.DID. US-5251268-$.DID. US-5214745-$.DID. US-4876731-$.DID. WO-0072449$.did. WO-9854653$.did. WO-9843159$.did. US-4874963-$.DID. US-4642782-$.DID. US-4660166-$.DID.) and 702/183.ccls.	USPAT; US-PGPUB; EPO	2004/05/10 15:14
-	0	hamalainen.in. and henriksson.in. and 702/183.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:14

-	1	(artificial adj neural adj network) and (pattern$1 same recogni$4 same classif$7) and (expert$1 adj system$1) and (knowledge adj base$1) and 702/183.ccls.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/05/10 15:14
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-	15	(US-5237508-$.DID. US-4958292-$.DID. US-4802094-$.DID. US-6269354-$.DID. US-6266668-$.DID. US-6262678-$.DID. US-6249755-$.DID. US-6216119-$.DID. US-5892808-$.DID. US-5835902-$.DID. US-5761383-$.DID. US-5748847-$.DID. US-5586033-$.DID. US-5528516-$.DID. US-5467428-$.DID. US-5448684-$.DID. US-5390261-$.DID. US-5376963-$.DID. US-5355435-$.DID. US-5253329-$.DID. US-5251268-$.DID. US-5214745-$.DID. US-4876731-$.DID. WO-0072449$.did. WO-9854653$.did. WO-9843159$.did. US-4874963-$.DID. US-4642782-$.DID. US-4660166-$.DID.) and threshold	USPAT; US-PGPUB; EPO	2004/05/10 19:50

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1 **LOGIC product yield analysis by wafer bin map pattern recognition supervised neural network**
Chen, F.L.; Sheng-Che Lin; Doong, K.Y.-Y.; Young, K.L.;
Semiconductor Manufacturing, 2003 IEEE International Symposium on , Sept Oct 2, 2003
Pages:501 - 504

[Abstract] [PDF Full-Text (376 KB)] **IEEE CNF**

2 **An artificial neural network-genetic based approach for time series forecasting**
Neves, J.; Cortez, P.;
Neural Networks, 1997. Proceedings., IVth Brazilian Symposium on , 3-5 Dec 1997
Pages:9 - 13

[Abstract] [PDF Full-Text (360 KB)] **IEEE CNF**

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1 **A method to design MMICs for high production yields**
Comparini, M.; Di Pasquale, A.; Feudale, M.; Giorgio, A.; Perri, A.G.;
Electronics, Circuits and Systems, 2002. 9th International Conference on , Vo
2 , 15-18 Sept. 2002
Pages:421 - 424 vol.2

[Abstract] [PDF Full-Text (410 KB)] **IEEE CNF**

2 **Micro yield modeling for IC processes**
Wong, A.Y.; Krott, L.C.;
TENCON '95. 1995 IEEE Region 10 International Conference on Microelectron and VLSI , 6-10 Nov. 1995
Pages:230 - 233

[Abstract] [PDF Full-Text (308 KB)] **IEEE CNF**

3 **Relation between product yield and plasma process induced damag**
Luchies, J.-M.; Simon, P.; Kuper, F.; Maly, W.;
Plasma Process-Induced Damage, 1998 3rd International Symposium on , 4-
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Pages:7 - 10

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4 **Prediction of product yield distributions from wafer parametric measurements of CMOS circuits**
Mizrukhin, L.; Heuy, J.; Mehta, S.;
Semiconductor Manufacturing, IEEE Transactions on , Volume: 5 , Issue: 2 ,
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Pages:88 - 93

[Abstract] [PDF Full-Text (524 KB)] **IEEE JNL**

5 **Optimal design and sequential analysis of VLSI testing strategy**
Yu, P.S.; Krishna, C.M.; Lee, Y.-H.;
Computers, IEEE Transactions on , Volume: 37 , Issue: 3 , March 1988
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[Abstract] [PDF Full-Text (732 KB)] **IEEE JNL**

6 **Oxygen control in Al-based III-V epiwafers by SIMS for yield improvement**
Gao, Y.; Mitha, S.; Huang, C.; Erickson, J.W.;
Indium Phosphide and Related Materials, 1997., International Conference on
15 May 1997
Pages:118

[Abstract] [PDF Full-Text (60 KB)] **IEEE CNF**

7 **Application of new control system for cold tandem mill**
Hitotsumatsu, E.; Ishibashi, T.; Okanoto, N.; Washikita, Y.; Nori, Y.;
Industry Applications Conference, 1996. Thirty-First IAS Annual Meeting, IAS Conference Record of the 1996 IEEE , Volume: 3 , 6-10 Oct. 1996
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[Abstract] [PDF Full-Text (420 KB)] **IEEE CNF**

8 **Ozone production using cylindrical reactors with and without solid dielectric layers in dry air**
Samaranayake, W.J.M.; Miyahara, T.; Namihira, T.; Katsuki, S.; Hackam, R.; Akiyama, H.;
Electrical Insulation and Dielectric Phenomena, 1999 Annual Report Conferen on , 17-20 Oct. 1999
Pages:379 - 382 vol.1

[Abstract] [PDF Full-Text (332 KB)] **IEEE CNF**

9 **Flux-free process for placement and attach of solder balls to wafers chips and all BGA packages**
Ramos, R.;
Electronics Manufacturing Technology Symposium, 1998. Twenty-Third IEEE/CPMT , 19-21 Oct. 1998
Pages:24 - 33

[Abstract] [PDF Full-Text (688 KB)] **IEEE CNF**

10 **A methodological approach to overcome the technology/equipmen inherited limitations for yield improvement**
Mao, M.; Chen, V.; Hsing, E.H.S.; Huang, H.; Shen, N.; Lin, R.; Chien, F.; Ye Yang, R.; Hong, J.;
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11 **Using computer simulation and robust design techniques to impro production yield [of electronic circuits]**
van Geest, E.; Mozar, S.;
Power Electronics and Drive Systems, 1995., Proceedings of 1995 Internation Conference on , 21-24 Feb. 1995
Pages:454 - 460 vol.1

[Abstract] [PDF Full-Text (448 KB)] **IEEE CNF**

12 **Defect density reduction in tungsten deposition and etchback**
Anderson, B.; Berezin, A.; Emami, I.;
Advanced Semiconductor Manufacturing Conference and Workshop. 1994. AS 94 Proceedings. IEEE/SEMI , 14-16 Nov. 1994
Pages:279 - 281

[Abstract] [PDF Full-Text (276 KB)] **IEEE CNF**

13 **Are environmental and manufacturing objectives compatible?**
Nusbaum, V.A.;
Electronics Manufacturing Technology Symposium, 1991., Eleventh IEEE/CHM International , 16-18 Sept. 1991
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[Abstract] [PDF Full-Text (248 KB)] **IEEE CNF**

14 **Knowledge-based electrical monitor approach using very large arr yield structures to delineate defects during process development and production yield improvement**
Hammond, J.; Sery, G.;
Defect and Fault Tolerance on VLSI Systems, 1991. Proceedings., 1991 International Workshop on , 18-20 Nov. 1991
Pages:67 - 80

[Abstract] [PDF Full-Text (568 KB)] **IEEE CNF**

15 **Generalization of Yield Optimization Problem: Maximum Income Approach**
Opalski, L.J.; Styblinski, M.A.;
Computer-Aided Design of Integrated Circuits and Systems, IEEE Transaction on , Volume: 5 , Issue: 2 , April 1986
Pages:346 - 360

[Abstract] [PDF Full-Text (2168 KB)] **IEEE JNL**

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1 VLSI circuit testing using and adaptive optimization model
P. S. Yu, C. M. Krishna, Y.-H. Lee
October 1987 **24th ACM/IEEE conference proceedings on Design automation conference**
Full text available: pdf(725.14 KB) Additional Information: full citation, abstract, references, index terms

The purpose of testing is to determine the correctness of the unit under test in come optimal way. One difficulty in meeting the optimality requirement is that the stochastic properties of the unit are usually unknown a priori. For instance, one might not know exactly the yield of a VLSI production line before one tests the chips made as a result. Given the probability of unit failure and the coverage of a test, the optimal test period is easy to obtain. However, the probability of failure ...

2 A multi-neural-network learning for lot sizing and sequencing on a flow-shop
In Lee, Jatinder N. D. Gupta, Amar D. Amar
March 2001 **Proceedings of the 2001 ACM symposium on Applied computing**
Full text available: pdf(52.28 KB) Additional Information: full citation, references, index terms

Keywords: flow-shop, lot sizing, neural networks, sequencing

3 CODAS: a data display system
R. H. Day, M. K. Mansfield, M. E. Ellis
February 1969 **Communications of the ACM**, Volume 12 Issue 2
Full text available: pdf(628.54 KB) Additional Information: full citation, abstract, citings, index terms

CODAS, a Customer Oriented Data System, is a user-oriented data retrieval and display system. The command language of the system provides the user with an easy means for specifying data retrieval and display requests. Data is displayed as tables and graphs produced in a format ready for publication. In this paper the statements of the request language and the general system design are described.

Keywords: command languages, data display, graphic display, information retrieval, managment data processing, report program generation

4 Simulation of a semiconductor manufacturing line
David J. Miller
October 1990 **Communications of the ACM**, Volume 33 Issue 10

Full text available: pdf(3.99 MB) Additional Information: full citation, abstract, references, citings, index terms, review

Product turnaround time (TAT) is defined as the clock or elapsed time from wafer release to completed wafer fabrication. It is also known as cycle time, mean elapsed time, or manufacturing lead time. Turnaround time is arguably more important in semiconductor fabrication than in any other industry because it has a major impact on contamination levels, process control capabilities, yield-learning rates and product costs. Semiconductor manufacturers must strictly control particulat ...

5 CMU-CAM system
Andrzej J. Strojwas
June 1985 **Proceedings of the 22nd ACM/IEEE conference on Design automation**

Full text available: pdf(811.28 KB) Additional Information: full citation, abstract, references, index terms

This paper describes a software system for Computer Aided Manufacturing (CAM) of VLSI circuits being developed at Carnegie-Mellon University. In developing the system, a major effort was devoted towards the computational efficiency of the algorithms implemented. The results obtained with this system indicate that it can be used for a variety of real-life tasks, such as optimal process design, process diagnosis and control, in commercial fabrication lines. We believe that such a system provi ...

6 Highlights of CMU research on CAD, CAM and CAT of VLSI circuits
John Paul Shen
November 1999 **Proceedings of 1986 fall joint computer conference on Fall joint computer conference**

Full text available: pdf(1.35 MB) Additional Information: full citation, references, index terms

7 Data mining solves tough semiconductor manufacturing problems
Mike Gardner, Jack Bieker
August 2000 **Proceedings of the sixth ACM SIGKDD international conference on Knowledge discovery and data mining**

Full text available: pdf(2.27 MB) Additional Information: full citation, references, index terms

Keywords: data mining, machine learning, manufacturing optimization, neural networks, pattern recognition, rule induction, self organizing maps, semiconductor yield enhancement

8 A representational language for qualitative process control
Richard M. Matejka, Thomas J. Lagnese
June 1988 **Proceedings of the first international conference on Industrial and engineering applications of artificial intelligence and expert systems - Volume 1**

Full text available: pdf(598.59 KB) Additional Information: full citation, abstract, references, index terms

This paper describes the Qualitative Process Control Environment (QPCE) which is used to prototype qualitative control systems. The language provided within this environment allows process engineers to place their knowledge about the process in an executable closed loop control system. We focus on one application, autoclave curing of composites, and use the QPCE to create a process control model. This work will demonstrate that the

process control model based upon event driven schedules wil ...

9 Design-manufacturing interface: Part II - applications
W. Maly, H. T. Heineken, J. Khare, P. K. Nag, P. Simon, C. Ouyang
February 1998 **Proceedings of the conference on Design, automation and test in Europe**

Full text available: pdf(75.88 KB) Publisher Site Additional Information: full citation, abstract, references, citings, index terms

This paper illustrates via examples problems at the design-manufacturing interface that exist in the IC industry today, and the ability of the YAN/PODEMA framework in solving these problems. The need for further development of the framework is also emphasized.

Keywords: manufacturability, yield, critical area, metal utilization, etch rate variation, antenna effect

10 A method for composing simple traditional music by computer
Gary M. Rader
November 1974 **Communications of the ACM**, Volume 17 Issue 11

Full text available: pdf(788.52 KB) Additional Information: full citation, abstract, references, citings, index terms

A method is described for composing musical rounds by computer. This method uses some music theory plus additional heuristics. Fundamental to the method is a set of productions together with sets of applicability rules and weight rules which operate on the productions deciding when and to what extent they are available for use. Several rounds generated by the computer implementation of the method are presented. Generally, the resultant music sounds mediocre to the professional al ...

Keywords: artificial intelligence, computer composition, computer music, formal languages, heuristic programming, models of cognitive processes, music theory, probabilistic grammars

11 Visualizing customer segmentations produce by self organizing maps (case study)
Holly Rushmeier, Richard Lawrence, George Almasi
October 1997 **Proceedings of the 8th conference on Visualization '97**

Full text available: pdf(780.01 KB) Publisher Site Additional Information: full citation, references, citings, index terms

12 An efficient, bus-layout based method for early diagnosis of bussed driver shorts in printed circuit boards
Kanad Chakraborty, Pinaki Mazumder
January 1997 **Proceedings of the 1996 IEEE/ACM international conference on Computer-aided design**

Full text available: pdf(79.83 KB) Publisher Site Additional Information: full citation, abstract, references, index terms

This paper presents a new, layout-based approach to board-level shorts diagnosis for bussed drivers, with the goal of early repair of interconnect shorts so as to minimize (a) fault masking during opens testing and (b) driver abuse. This approach leads to an early diagnosis of more than 96% of shorts and simplifies the subsequent rest for opens considerably. Besides, this approach improves the production yield and field survivability of

boards.

Keywords: bus-layout, bussed driver shorts, early diagnosis, field survivability, interconnect shorts, printed circuit boards, printed circuit testing, production yield

13 The simulation of cluster tools: a new semiconductor manufacturing technology
H. Todd LeBaron, Mark Pool
December 1994 **Proceedings of the 26th conference on Winter simulation**

Full text available: pdf(599.49 KB) Additional Information: full citation, references, citings, index terms

14 A "grid-free" channel router
Koji Sato, Hiroyoshi Shimoyama, Takao Nagai, Masaru Ozaki, Toshihiko Yahara
June 1980 **Proceedings of the seventeenth design automation conference on Design automation**

Full text available: pdf(886.28 KB) Additional Information: full citation, abstract, references, citings, index terms

A "grid-free" channel router (termed GFR) is reported. GFR does not employ grid lines and can obtain better results than the fixed-grid method. Additionally, GFR has several optional functions, such as "constraint loop breaking", "total branch length minimization", "constraint chain cutting" and "layer changing". The algorithms of these functions are outlined and results obtained by using them are presented.

15 On software development to support statistical simulation of analogue circuits
E. Driouk, O. Jarov, A. Sukhodolsky
March 1995 **Proceedings of the 1995 European conference on Design and Test**

Full text available: pdf(558.96 KB) Publisher Site Additional Information: full citation, abstract

A system for statistical circuit analysis, yield estimation and design centering is presented. The system architecture is based on the decomposition of the simulation process into three logically independent layers. A dedicated language is a significant part of the system. Its syntax implements an advanced technique that allows one to create flexible circuit performance extraction procedures. An application example demonstrates the system capabilities.

Keywords: analogue circuits, analogue integrated circuits, circuit analysis computing, circuit performance extraction procedures, dedicated language, design centering, integrated circuit yield, software development, software engineering, statistical analysis, statistical circuit analysis, statistical simulation, yield estimation

16 Semiconductor manufacturing: A simulation-based cost modeling methodology for evaluation of interbay material handling in a semiconductor wafer fab
Shari Murray, Gerald T. Mackulak, John W. Fowler, Theron Colvin
December 2000 **Proceedings of the 32nd conference on Winter simulation**

Full text available: pdf(2.08 MB) Additional Information: full citation, abstract, references, citings

In the next generation of semiconductor wafer fabrication facilities, decisions concerning material handling systems will be a major factor in initial facility cost, operational cost, production cycle times, and possibly product yield percentages. The wafers will increase in diameter to 300 mm and a new front opening unified pod (FOUP) has been designed to carry them, both increasing the weight of a production lot. This increase requires

substantial automation for ergonomic and quality reasons. ...

17 Design-manufacturing interface: Part I — vision

W. Maly, H. T. Heineken, J. Khare, P. K. Nag

February 1998 **Proceedings of the conference on Design, automation and test in Europe**

Full text available: pdf(142.42 KB) Publisher Site Additional Information: full citation, abstract, references, citings, index terms

This paper proposes a vision for a new research domain emerging on the interface between design and manufacturing of VLSI circuits. The key objective of this domain is the minimization of the mismatch between design and manufacturing which is rapidly growing with the increase in complexity of VLSI designs and IC technologies. This broad objective is partitioned into a number of specific tasks. Often, one of the most important tasks is the extraction of VLSI design attributes that may be relevant ...

Keywords: manufacturability, yield, design, design rules, synthesis

18 Proving termination with multiset orderings

Nachum Dershowitz, Zohar Manna

August 1979 **Communications of the ACM**, Volume 22 Issue 8

Full text available: pdf(1.12 MB) Additional Information: full citation, abstract, references, citings

A common tool for proving the termination of programs is the well-founded set, a set ordered in such a way as to admit no infinite descending sequences. The basic approach is to find a termination function that maps the values of the program variables into some well-founded set, such that the value of the termination function is repeatedly reduced throughout the computation. All too often, the termination functions required are difficult to find and are of ...

Keywords: bags, multisets, production systems, program correctness, program termination, program verification, reduction rules, term rewriting systems, tree replacement systems, well-founded orderings, well-founded sets

19 Applying the simulation process

Jerry Banks, John S. Carson

December 1988 **Proceedings of the 20th conference on Winter simulation**

Full text available: pdf(390.16 KB) Additional Information: full citation, abstract, references, index terms

The purpose of this tutorial is to explain the steps required in conducting an entire simulation project. We first explain the twelve steps we consider necessary to accomplish a thorough simulation study. Then we describe three projects that the authors have completed. We discuss the systems, model assumptions, and input data for these projects. During the tutorial, we illustrate how the twelve steps pertain to the three simulation studies.

20 Simulation metamodels

Russell R. Barton

December 1998 **Proceedings of the 30th conference on Winter simulation**

Full text available: pdf(79.38 KB) Additional Information: full citation, references, citings, index terms

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1 **On CD coat weight control**
Ismail, A.; Dumont, G.; Backstrom, J.;
American Control Conference, 2001. Proceedings of the 2001 , Volume: 3 , 2
June 2001
Pages:2231 - 2237 vol.3

[Abstract] [PDF Full-Text (456 KB)] **IEEE CNF**

2 **A simulation-based cost modeling methodology for evaluation of interbay material handling in a semiconductor wafer fab**
Murray, S.; Mackulak, G.T.; Fowler, J.W.; Colvin, T.;
Simulation Conference Proceedings, 2000. Winter , Volume: 2 , 10-13 Dec. 2
Pages:1510 - 1517 vol.2

[Abstract] [PDF Full-Text (588 KB)] **IEEE CNF**

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1 Data clustering: a review

A. K. Jain, M. N. Murty, P. J. Flynn

September 1999 **ACM Computing Surveys (CSUR)**, Volume 31 Issue 3

Full text available: pdf(636.24 KB) Additional Information: full citation, abstract, references, citings, index terms, review

Clustering is the unsupervised classification of patterns (observations, data items, or feature vectors) into groups (clusters). The clustering problem has been addressed in many contexts and by researchers in many disciplines; this reflects its broad appeal and usefulness as one of the steps in exploratory data analysis. However, clustering is a difficult problem combinatorially, and differences in assumptions and contexts in different communities has made the transfer of useful generic co ...

Keywords: cluster analysis, clustering applications, exploratory data analysis, incremental clustering, similarity indices, unsupervised learning

2 Artificial neural network models for texture classification via: the Radon transform

A. D. Kulkarni, P. Byars

March 1992 **Proceedings of the 1992 ACM/SIGAPP symposium on Applied computing: technological challenges of the 1990's**

Full text available: pdf(448.54 KB) Additional Information: full citation, references, index terms

3 Face recognition: A literature survey

W. Zhao, R. Chellappa, P. J. Phillips, A. Rosenfeld

December 2003 **ACM Computing Surveys (CSUR)**, Volume 35 Issue 4

Full text available: pdf(4.26 MB) Additional Information: full citation, abstract, references, index terms

As one of the most successful applications of image analysis and understanding, face recognition has recently received significant attention, especially during the past several years. At least two reasons account for this trend: the first is the wide range of commercial and law enforcement applications, and the second is the availability of feasible technologies after 30 years of research. Even though current machine recognition systems have reached a certain level of maturity, their success is ...

Keywords: Face recognition, person identification

4 Position papers: Artificial neural networks: a science in trouble
Asim Roy
January 2000 **ACM SIGKDD Explorations Newsletter**, Volume 1 Issue 2

Full text available: pdf(646.93 KB) Additional Information: full citation, abstract, references

This article points out some very serious misconceptions about the brain in connectionism and artificial neural networks. Some of the connectionist ideas have been shown to have logical flaws, while others are inconsistent with some commonly observed human learning processes and behavior. For example, the connectionist ideas have absolutely no provision for learning from stored information, something that humans do all the time. The article also argues that there is definitely a need for some ne ...

Keywords: artificial neural networks, automated learning, brain-like learning, connectionism, data mining, intelligent systems

5 Pattern recognition with a pulsed neural network
Judith Dayhoff
May 1991 **Proceedings of the conference on Analysis of neural network applications**

Full text available: pdf(1.16 MB) Additional Information: full citation, references, index terms

6 Self organizing neural networks with a split/merge algorithm
A. D. Kulkarni, G. M. Whitson
February 1990 **Proceedings of the 1990 ACM SIGSMALL/PC symposium on Small systems**

Full text available: pdf(525.13 KB) Additional Information: full citation, abstract, references, index terms

In this paper we present a new learning algorithm for Artificial Neural Networks (ANN) using a split/merge technique. An ANN model with the new algorithm has been developed and tested on a PC. The model detects the similarity between the input patterns, and identifies the number of categories present in the input samples. The algorithm is similar to a competitive learning algorithm. Unlike the competitive learning algorithm, in this algorithm we use two types of weights: long term weights (...

7 Continuous learning: a design methodology for fault-tolerant neural networks
Vincenzo Piuri
June 1990 **Proceedings of the third international conference on Industrial and engineering applications of artificial intelligence and expert systems - Volume 2**

Full text available: pdf(1.36 MB) Additional Information: full citation, abstract, references, index terms

Fault tolerance in artificial neural networks is an important feature, in particular when the application is critical or when maintenance is difficult. This paper presents a general design methodology for designing fault-tolerant architectures, starting from the behavioral description of the nominal network and from the nominal algorithm. The behavioral level is considered to detect errors due to hardware faults, while system survival is guaranteed by the reactivation of learning mechanisms ...

8 A verification methodology for computer systems users
M. S. Obaidat
February 1995 **Proceedings of the 1995 ACM symposium on Applied computing**

Full text available: pdf(661.61 KB) Additional Information: full citation, references, index terms

Keywords: classification, interkey times, key hold times, neural networks

9 Poster: A two-stage fingerprint classification system

Raffaele Cappelli, Dario Maio, Davide Maltoni, Loris Nanni

November 2003 **Proceedings of the 2003 ACM SIGMM workshop on Biometrics methods and applications**

Full text available: pdf(607.18 KB) Additional Information: full citation, abstract, references, index terms

In this paper we describe a fingerprint classification system based on a two-stage sequential architecture: an MKL-based classifier is first used to select the two-most-likely classes and then a second classifier (specifically trained to discriminate between the two classes) is then adopted for the final decision. The experimentation performed on NIST Special Database 4, which is one of the most important benchmarks in this area, shows that the new approach yields an error rate lower than previo ...

Keywords: classifier combination, directional image, feature selection, fingerprint classification, subspace classifiers

10 Analyzing human gait patterns for maifunction detection

Monika Köhle, Dieter Merkl

March 2000 **Proceedings of the 2000 ACM symposium on Applied computing**

Full text available: pdf(357.35 KB) Additional Information: full citation, references, index terms

Keywords: Radial Basis Function networks, gait analysis, pattern classification

11 A don't care back propagation algorithm applied to satellite image recognition

Antonette Logar, Edward Corwin, Samuel Watters, Ronald Weger, Ronald Welch

April 1994 **Proceedings of the 1994 ACM symposium on Applied computing**

Full text available: pdf(477.16 KB) Additional Information: full citation, references, index terms

12 Data mining of multidimensional remotely sensed images

Robert F. Cromp, William J. Campbell

December 1993 **Proceedings of the second international conference on Information and knowledge management**

Full text available: pdf(1.39 MB) Additional Information: full citation, references, citings, index terms

13 Scalable feature selection, classification and signature generation for organizing large text databases into hierarchical topic taxonomies

Soumen Chakrabarti, Byron Dom, Rakesh Agrawal, Prabhakar Raghavan

August 1998 **The VLDB Journal — The International Journal on Very Large Data Bases**, Volume 7 Issue 3

Full text available: pdf(281.37 KB) Additional Information: full citation, abstract, citings, index terms

We explore how to organize large text databases hierarchically by topic to aid better

searching, browsing and filtering. Many corpora, such as internet directories, digital libraries, and patent databases are manually organized into topic hierarchies, also called *taxonomies*. Similar to indices for relational data, taxonomies make search and access more efficient. However, the exponential growth in the volume of on-line textual information makes it nearly impossible to maintain such taxono ...

14 CMU-CAM system
Andrzej J. Strojwas
June 1985 **Proceedings of the 22nd ACM/IEEE conference on Design automation**

Full text available: pdf(811.28 KB) Additional Information: full citation, abstract, references, index terms

This paper describes a software system for Computer Aided Manufacturing (CAM) of VLSI circuits being developed at Carnegie-Mellon University. In developing the system, a major effort was devoted towards the computational efficiency of the algorithms implemented. The results obtained with this system indicate that it can be used for a variety of real-life tasks, such as optimal process design, process diagnosis and control, in commercial fabrication lines. We believe that such a system provi ...

15 ANNIE: a simulated neural network for empirical studies and application prototyping
Wendy L. Huxhold, Troy F. Henson, J. Dan Bowman
April 1992 **Proceedings of the 25th annual symposium on Simulation**

Full text available: pdf(660.67 KB) Additional Information: full citation, references, index terms

16 Optimal path analysis using a predator-prey neural network model
Scott M. Huse
June 1990 **Proceedings of the third international conference on Industrial and engineering applications of artificial intelligence and expert systems - Volume 2**

Full text available: pdf(3.49 MB) Additional Information: full citation, abstract, references, index terms

A neural network research effort is currently underway at Rome Air Development Center, the Intelligence and Reconnaissance Division (RADC/IR). Griffiss Air Force Base. The purpose of this research is to solve computationally difficult intelligence exploitation problems that have eluded conventional techniques, e.g., target recognition, battlefield multi-sensor correlation and fusion, and intelligence situation assessment. This paper describes the use of a predator-prey neural net ...

17 PAC-like upper bounds for the sample complexity of leave-one-out cross-validation
Sean B. Holden
January 1996 **Proceedings of the ninth annual conference on Computational learning theory**

Full text available: pdf(932.41 KB) Additional Information: full citation, references, citings, index terms

18 A new approach for evolving clusters
Robert E. Marmelstein, Gary B. Lamont
February 1999 **Proceedings of the 1999 ACM symposium on Applied computing**

Full text available: pdf(709.36 KB) Additional Information: full citation, references, index terms

19
Industry track papers: Mining heterogeneous gene expression data with time lagged

recurrent neural networks
Yulan Liang, Arpad Kelemen
July 2002 **Proceedings of the eighth ACM SIGKDD international conference on Knowledge discovery and data mining**
Full text available: pdf(1.48 MB) Additional Information: full citation, abstract, references, index terms

Heterogeneous types of gene expressions may provide a better insight into the biological role of gene interaction with the environment, disease development and drug effect at the molecular level. In this paper for both exploring and prediction purposes a Time Lagged Recurrent Neural Network with trajectory learning is proposed for identifying and classifying the gene functional patterns from the heterogeneous nonlinear time series microarray experiments. The proposed procedures identify gene fun ...

Keywords: backpropagation through time, gene expression, heterogeneous, time lagged neural network, trajectory learning

20 Fuzzy rule extraction from GIS data with a neural fuzzy system for decision making
Ding Zheng, Wolfgang Kainz
November 1999 **Proceedings of the seventh ACM international symposium on Advances in geographic information systems**
Full text available: pdf(1.07 MB) Additional Information: full citation, references, index terms

Keywords: GIS, decision-making, fuzzy rule inference, neural network

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